



<b>Form 1449 (Modified)</b>  <b>Information Disclosure Statement By Applicant</b>  <b>(Use Several Sheets if Necessary)</b>	<b>Atty Docket No.</b> <b>NOVLP075/NVLS-000820</b>  <b>Applicant:</b> <b>Tipton et al.</b>  <b>Filing Date</b> <b>September 26, 2003</b>	<b>Application No.:</b> <b>10/672,311</b>  <b>Group</b> <b>2823</b>
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## **U.S. Patent Documents**

### **Foreign Patent or Published Foreign Patent Application**

## **Other Documents**

Other Documents		
Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	C1	Cho et al., "Method for Porogen Removal and Mechanical Strength Enhancement of Low-K Carbon Doped Silicon Oxide Using Low Thermal Budget Microwave Curing", U.S. Application No. 11/280,113, filed November 15, 2005 (Atty Dkt: NOVLP145/NVLS-3106)
Examiner 	Date Considered 	

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.